

APPARATUS AND METHOD FOR INSPECTING ARRAY SUBSTRATE

ABSTRACT

An object of the present invention is to provide an apparatus and a method for detecting a defective pixel caused by a punch-through voltage that cannot be detected by a conventional apparatus for inspecting an array substrate. An apparatus for inspecting an array substrate according to the present invention comprises: means for applying a first voltage VGH1 to switching elements so as to accumulate electric charges in storage capacitors and gate-electrode capacitors of the array substrate; and means for applying a second voltage VGH2 having a different voltage value than the first voltage VGH1 has to the switching elements when the electric charges accumulated in the storage capacitors and the gate-electrode capacitors are read.